

BT 150 & 300

Bench Top Coaters

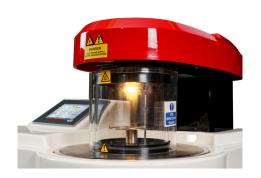


The HHV BT 150 and BT 300 bench top coating systems are compact and economical solutions designed to suit the needs of electron microscopists and researchers across various disciplines. These systems feature a fully-automated interface to provide a hassle-free single-touch processing capability.

The systems are designed to prepare specimens for scanning electron microscopy by metal sputtering, for transmission electron microscopy and x-ray micro analysis by carbon evaporation from fibre and rods.

CHAMBER CONFIGURATIONS

BT 150



BT 150 Chamber



Magnetron Sputtering



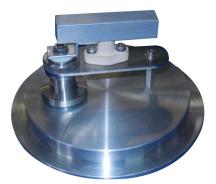
Thermal Evaporation



Carbon Rod Evaporation

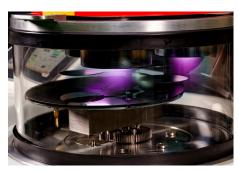


Carbon Fibre Evaporation



Glow Discharge Source

BT 300



BT 300 Chamber

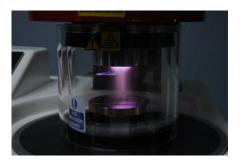


Dual Sputter Source

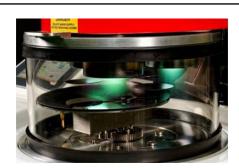


Triple Sputter Source

SAMPLE STAGE



Static Sample Stage



Planetary Sample Stage

SPECIFICATIONS

CHAMBER SIZE BT 150: 165 mm Ø x 150 mm tall

BT 300: 300 mm Ø x 150 mm tall

Chamber made of glass, and is provided with implosion guard.

Option for 200 mm tall chamber.

ROUGHING PUMP OPTIONS 2-stage Rotary Pump/Dry Scroll Pump

HV PUMPING Optional Turbo Pump with Penning gauge

PUMPING TIME 5 x 10-2 mbar: < 3 min (BT 150), < 12 min (BT 300)

5 x 10-5 mbar: < 8 min (BT 150), < 20 min (BT 300)

SAMPLE STAGE OPTIONS BT 150

- Static stage with water cooling and biasing options for upto 100 mm

diameter samples.

- Rotary stage options for 6 stubs, and upto 100 mm diameter samples.

- Planetary stage for 6 stubs.

BT 300

 Planetary stage options with 2-position indexing for samples upto 50 mm diameter (dual target), and continuous rotation for 200 mm diameter.

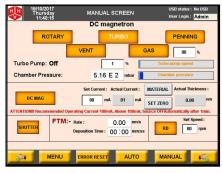
OPTIONAL ACCESSORIES Quartz crystal film thickness monitor

CONTROL OPTIONS

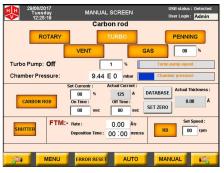
Touch-screen HMI based operation with manual and auto modes.



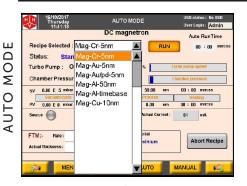
Manual Mode



Magnetron Source



Carbon Source



Recipe Selection



Recipe Edit



Auto Cycle Operation

Remote connectivity facility for factory support

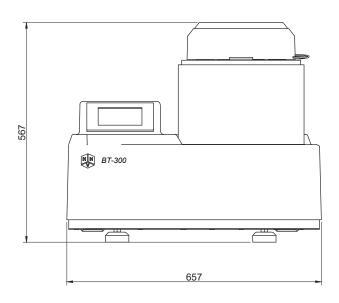
FEATURES

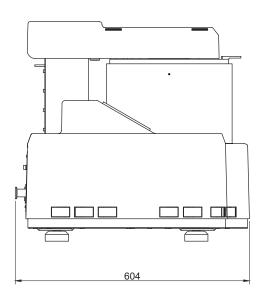
APPLICATIONS

- Single touch automated process
- Process data output to mass storage device or PC
- Easy source change-over
- Automatic recognition of deposition accessories
- Maximum flexibility in programming process sequence
- Compact unit minimizing footprint

- Electron microscopy
- Metallization
- Surface modification
- Two layer contacts for electronic devices
- TCO coatings
- X-ray microanalysis

LAYOUT





All dimensions in mm



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